

FORM PTO-1449
INFORMATION DISCLOSURE STATEMENT

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APPLICATION NO.
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APPLICANT
NELSON *et al.*

FILING DATE
April 25, 2001

GROUP
2851

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE
	AA1						
	AB1						
	AC1						
	AD1						
	AE1						
	AF1						
	AG1						
	AH1						
	AI1						
	AJ1						
	AK1						

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FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION
	AL1						Yes No
	AM1						Yes No
	AN1						Yes No
	AO1						Yes No
	AP1						Yes No


OTHER (Including Author, Title, Date, Pertinent Pages, etc.)

DBE	AR	1	Advanced Focus System Development Task Proposal Submitted in response to Advanced Lithography SOL BAA 99-14, March 2, 1999, pp. 1-34, Silicon Valley Group, Inc., Lithography Division
	AS	1	
	AT	1	

EXAMINER



DATE CONSIDERED



EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.